

Please type a plus sign (+) inside this box → +

PTO/SB/08A (08-00)

Approved for use through 10/31/2002. OMB 0651-0031

U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 1

Complete if Known

Application Number	TBA
Filing Date	December 6, 2001
First Named Inventor	Hatakeyama et al.
Group Art Unit	TBA
Examiner Name	TBA
Attorney Docket Number	KOJIM-440

JC675 U.S. PTO 10/003288

12/06/01

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
S. J. L.	A	4,491,628		Ito et al.	01/01/1985	
	B	5,310,619		Crivello et al.	05/10/1994	
	C	5,580,695		Murata et al.	12/03/1996	
	D	5,609,989		Bantu et al.	03/11/97	

FOREIGN PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ₆
		Office ³	Number ⁴	Kind Code ⁵ (if known)				
S. J. L.	E	JP	90027660	B	Frechet et al.	06/19/1990		
	F	JP	63027829	A	Crivello et al.	02/05/1988		
	G	WO	9837458	A1	Sone et al.	08/27/1998		
	H	JP	63149640	A		06/22/1988		
	I	JP	5113666	A		05/07/1993		
	J	JP	5232706	A	Kobayashi et al.	09/10/1993		
	K	JP	5249683	A	Kobayashi et al.	09/28/1993		

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
S. J. L.	L	Hinsberg et al., "Fundamental Studies of Airborne Chemical Contamination of Chemically Amplified Resists," <i>Journal of Photopolymer Science and Technology</i> , Vol. 6, No. 4 (1993) pp 535-546.	
	M	Kumada, et al., "Study on Over-Top Coating of Positive Chemical Amplification Resists for KrF Excimer Laser Lithography," <i>Journal of Photopolymer Science and Technology</i> , Vol. 6, No. 4 (1993) pp 571-574.	
	N	Hatakeyama, et al., "Investigation of Discrimination Enhancement with New Modeling for Poly-hydroxystyrene Positive Resists," <i>Journal of Photopolymer Science and Technology</i> , Vol. 13, No. 4 (2000) pp 519-524.	

Examiner Signature

Sin J. Lee

Date Considered

Sept. 5, 2003

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.